

updated

Freeform Search

Database:	<div>US Pre-Grant Publication Full-Text Database US Patents Full-Text Database US OCR Full-Text Database EPO Abstracts Database JPO Abstracts Database Derwent World Patents Index IBM Technical Disclosure Bulletins</div>
Term:	<div>(first focal near array or second focal near array or first FPA or second FPA)</div>
Display:	<div>10 Documents in Display Format: Starting with Number 1</div>
Generate:	<div><input type="radio"/> Hit List <input checked="" type="radio"/> Hit Count <input type="radio"/> Side by Side <input type="radio"/> Image</div>

Search

Clear

Interrupt

Search History

DATE: Friday, October 26, 2007 [Purge Queries](#) [Printable Copy](#) [Create Case](#)

Set
Name Query

side by
side

DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ

L28 (first focal near array or second focal near array or first FPA or second FPA)

L27 L22 and (first focal or second focal or first FPA or second FPA)

DB=USPT; PLUR=YES; OP=ADJ

L26 10554140

DB=PGPB,USPT,USOC,EPAB,JPAB; PLUR=YES; OP=ADJ

L25 L17 and (reference near sample or reference near target or reference near object or reference near

L24 L22 and (thermal near scan\$4 or temperature near scan\$4 or thermal imag\$3 or temperature imag

L23 L22 and (thermal near map\$4 or temperature near map\$4)

L22 L17 and (reference near sample or reference near target or reference near object or reference near

L21 L17 and (calibrat\$3 near map\$4)

L20 L19 and (calibrat\$3 near map\$3)

L19 L18 and (calibrat\$3 or reference)

L18 L17 and (focal plane array or FPA)

L17 (374/1,2,120,121,124,129;250/252.1,338.1,339.02,339.03,339.04,339.09,339.11,341.5,393)![CCI

DB=USPT; PLUR=YES; OP=ADJ

L16 5846276.pn.

L15 6331075.pn.

L14 5693685.pn.

L13 6993926.pn.

L12 L10

L11 L10

L10 6571569.pn.

DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ

L9 L8 and L5

L8 L7 and (flow sensor or flux sensor or flow meter or flux near meter or flow transducer or flux near thermal flux or heat flow path or heat transfer or thermal transfer)

L7 (MEMS or micro near mechanical or nano near mechanical) near5 (manufacturing or producing o

DB=PGPB,USPT,USOC,EPAB,JPAB; PLUR=YES; OP=ADJ

L6 L5 and L3

L5 (374/29,43,44,31,137,141,142,143,144,147,10,39,30,100;29/592.1,595;522/1.169,172;427/249.1, [CCLS]

DB=PGPB,USPT,USOC,EPAB,JPAB,DWPI,TDBD; PLUR=YES; OP=ADJ

L4 L3 and (polymer near precursor)

L3 L2 and (flow sensor or flux sensor or flow meter or flux near meter or flow transducer or flux near thermal flux or heat flow path or heat transfer or thermal transfer)

L2 (MEMS or micro near mechanical or nano near mechanical) near5 (manufacturing or producing o

L1 (MEMS or micro near mechanical or nano near mechanical) and (manufacturing or producing or)

END OF SEARCH HISTORY